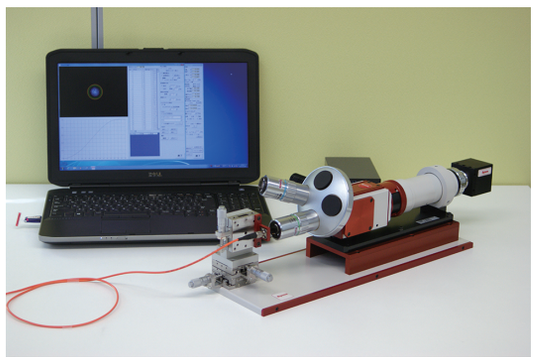
OPTICAL BEAM NFP MEASUREMENT SYSTEM

Optical beam profile measurement system in combination with NFP measurement optics & image processing.



【Product overview】

Optical beam NFP (Near Field Pattern) measurement system is general purpose beam profiler system, widely applicable from optical beam observation to highly advanced optical beam analysis.

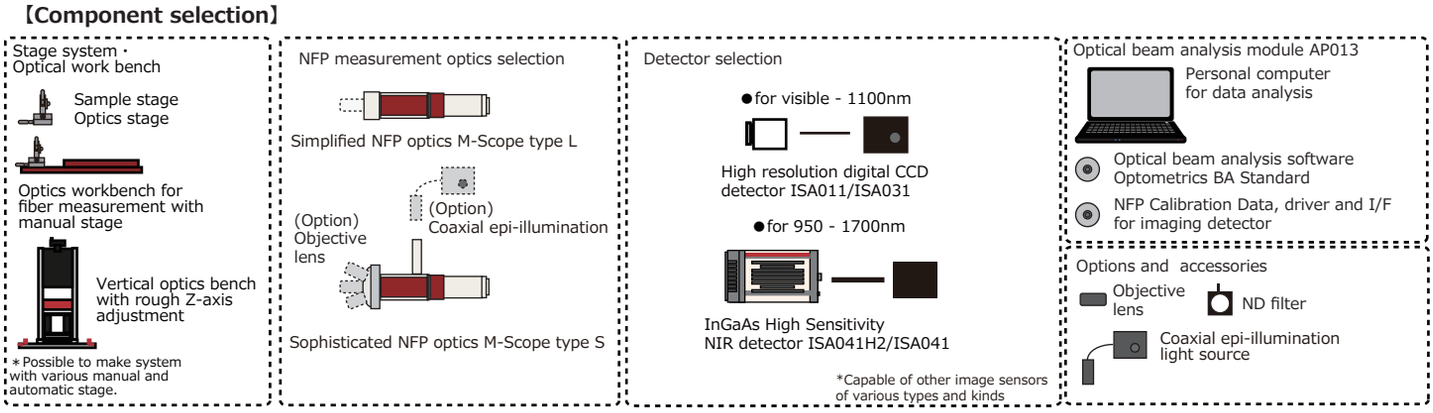
【Feature】

- Synos' **M-Scope type S**, sophisticated NFP measurement optics, is adopted as NFP measurement optics
  - *Widely applicable for various optical beam pattern analysis
  - *Equipping manual revolver to switch multiple objective lens
  - *Equipping coaxial epi-illumination port for image observation
  - *Possible to select **M-Scope type L**, inexpensive-type NFP optics
- By selecting detector, it will be applicable for optical beam profile observation and analysis from visible to NIR wavelength.
  - *For visible-1100nm: **ISA011**, high resolution digital CCD detector
  - *For 950nm-1700nm: **ISA041H2**, InGaAs high sensitivity NIR detector
- Optical beam analysis module **AP013**, specially designed high-functional image processing system for optical beam profile analysis
  - *Essential and useful functionality for NFP, FFP, beam profile analysis, EF/EAF analysis are equipped in Synos' original optical beam analysis software **Optometrics BA Standard**.
- High system expandability with various optional units
  - *In combination with various positioning stages, measurement instruments such as optical powermeter, source meter, various system, it is possible to build up advanced optical measurement system.

【Application】

- NFP measurement, optial beam pattern and beam quality analysis of various light emitted device such as laser, laser diode, and so on.
- NFP measurement , MFD observation and measurement of various optical fibers such as SMF, MMF, POF and so on.
- NFP measurement , optical beam pattern analysis, edge face observation of waveguide modules, OPCB waveguide and so on.
- NFP measurement, optial beam pattern and beam quality analysis of various optical modules.
- Encircled flux analysis of various MMF (Mmulti-mode optical fiber)

【Component selection】



*A variety of system setup is possible depending on the purpose and application. Please feel free to contact us.

【Main component】

- NFP measurement optics selection
  - *Sophisticated NFP measurement optics **M-Scope type S**, with Manual revolver, coaxila epi-illumination port
  - *Simplified NFP measurement optics **M-Scope type L**, monocular and inexpensive-type
  - ☞*About NFP measurement optics in details, please refer to P7.*
- Image sensor selection (recommendation)
  - *For visible - 1100nm: Synos' Hi-resolution digital CCD detector **ISA011/ISA031**
  - *For 950nm - 1700nm: Synos' InGaAs high sensitivity NIR detector **ISA041H2**
  - ☞*About imaging detector in details, please refer to P25-28.*
- Optical beam analysis module AP-013
  - *Personal Computer system for data analysis
  - *Image processor board & interface board set
  - *Optical beam analysis software : Optometrics BA Standard (Optometrics BA Standard main program, calibration data set, driver and I/F software for imaging detector)
  - ☞*About AP013 in details, please refer to P24.*
- Standard accessories
  - *Cables, manuals

【Option, accessory】

- Objective lens
  - *Please select appropriate object lens in specification of pixel resolution, N.A., measurement field of view, measurement wavelength, sample, etc.
  - ☞*About objective lens in details, please refer to P31.*
- ND filter
  - *Possible to supply due to attenation ratio, measurement wavelength, etc.
  - ☞*About ND filter in details, please refer to P31.*
- Coaxial epi-illumination light source
  - *LED type (for visible - 850nm wavelength range)
  - *Halogen type (for NIR wavelength range)
  - ☞*About coaxial epi-illumination light source in details, please refer to P32.*
- Optical workbench
  - *Optical workbench for fiber measurement
  - *Vertical setup optical workbench
  - ☞*About optical workbench in details, please refer to P32.*